

Analysis of Micromegas Large Prototype data



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3rd analysis meeting - June 22, 2009

- Comparison between two resistive modules
- Resolution measurements
- Distortions
- Momentum resolution

- Three panels were successively mounted and tested in the Large Prototype and 1T magnet:
 - standard anode
 - resistive anode (carbon loaded kapton) with a resistivity $\sim 2.8 \text{ M}\Omega/\square$
 - resistive ink ($\sim 1\text{-}2 \text{ M}\Omega/\square$) ready for next beam tests
- November 2008
- May-June 2009

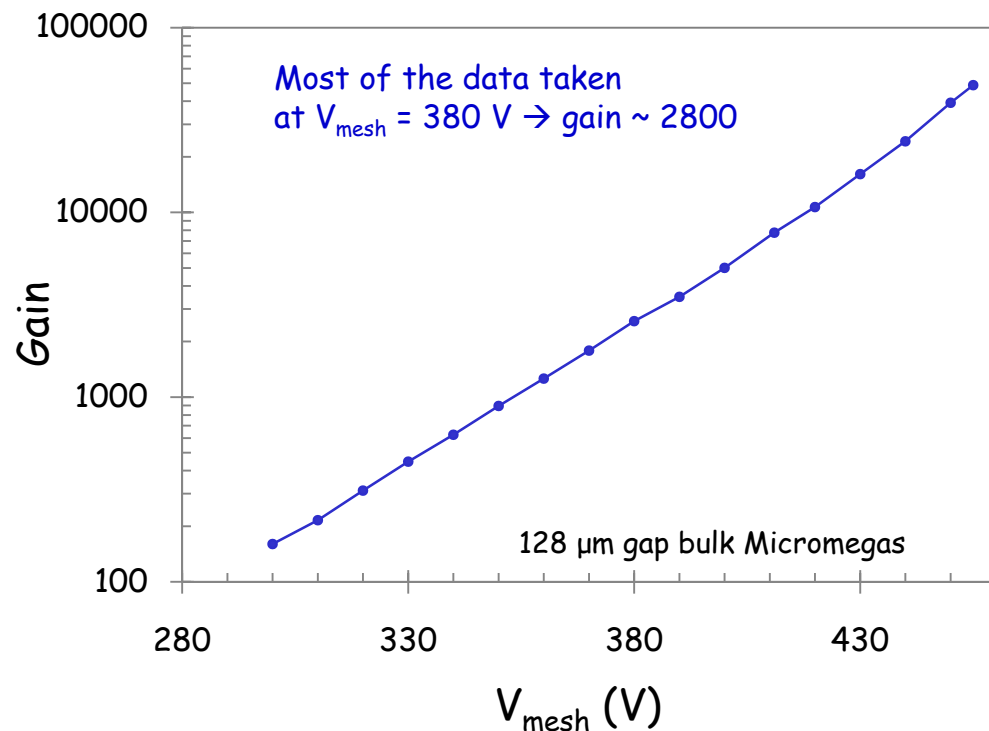


Standard bulk Micromegas module



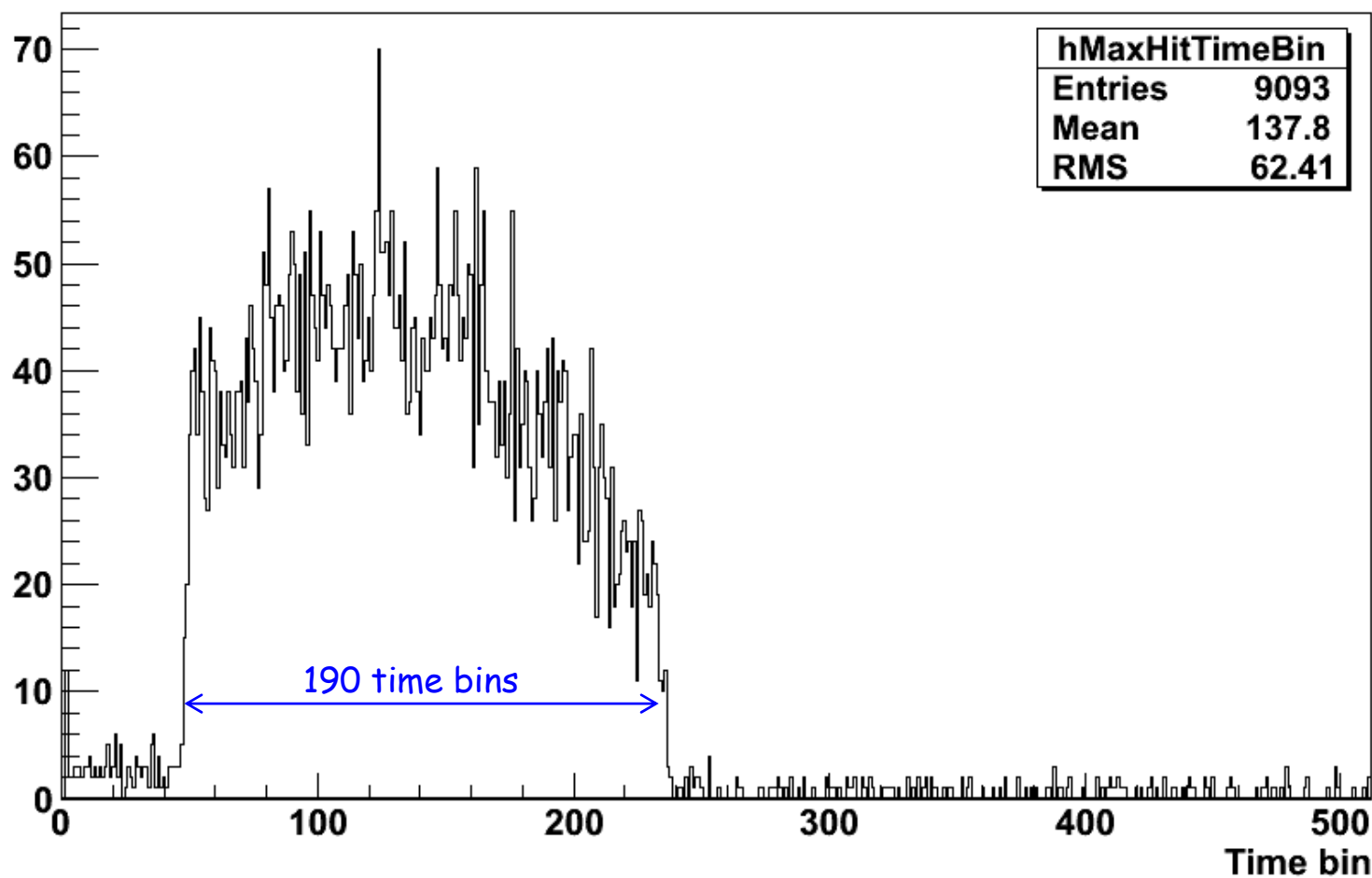
Carbon loaded kapton Micromegas module

- Bulk Micromegas detector: 1726 (24x72) pads of $\sim 3 \times 7 \text{ mm}^2$
- AFTER-based electronics (72 channels/chip):
 - low-noise (700 e-) pre-amplifier-shaper
 - 100 ns to 2 μs tunable peaking time
 - full wave sampling by SCA
 - frequency tunable from 1 to 100 MHz (most data at 25 MHz)
 - 12 bit ADC (rms pedestals 4 to 6 channels)
- Beam data (5 GeV electrons) were taken at several z values by sliding the TPC in the magnet. Beam size was 4 mm rms.

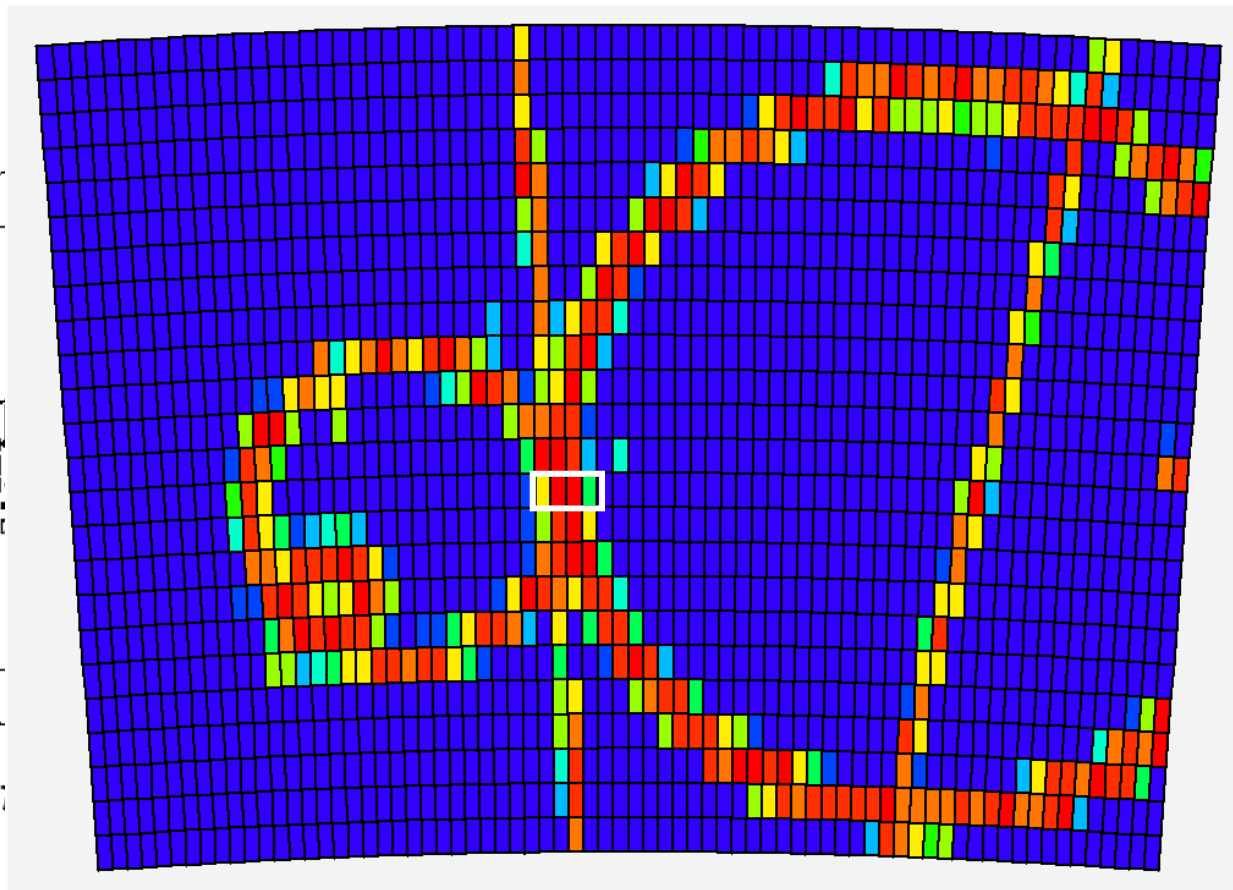
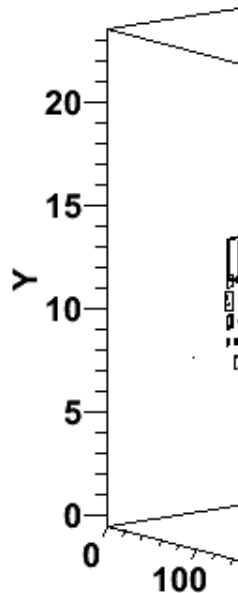


- cosmic run at 25 MHz of sampling frequency \rightarrow time bin = 40 ns
- TPC length = 56.85 cm in agreement with survey

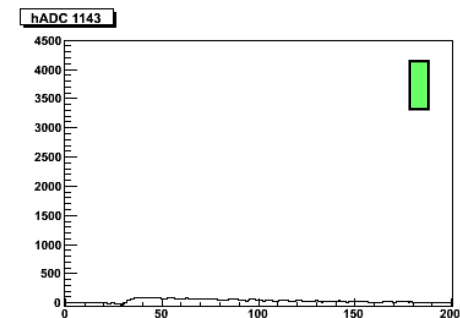
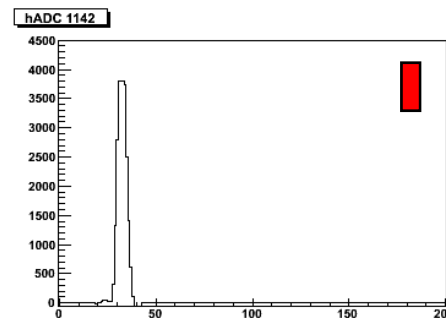
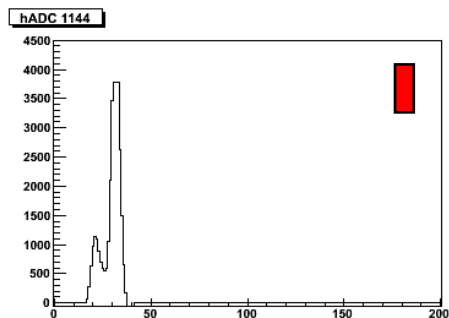
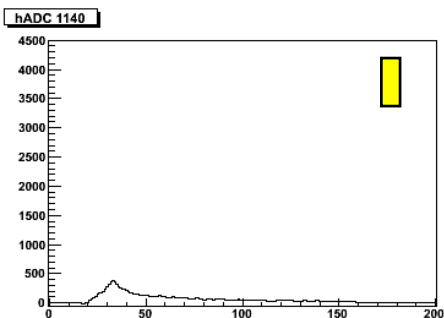
hMaxHitTimeBin

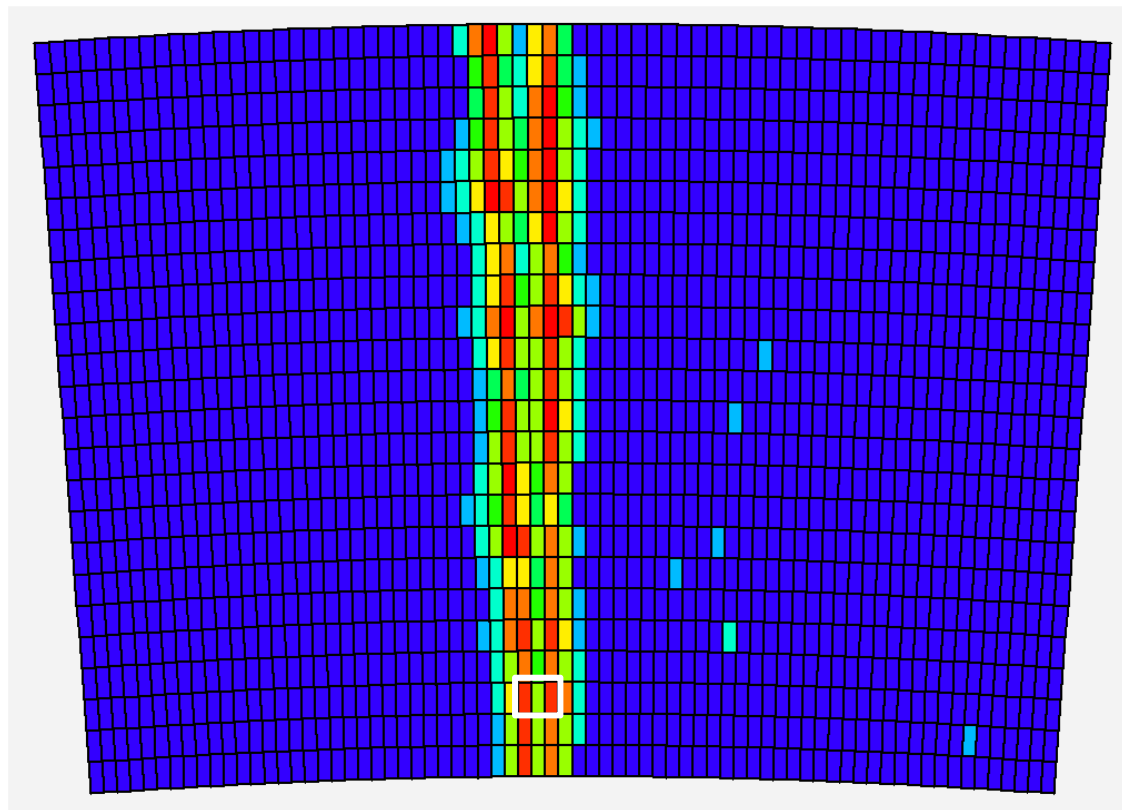
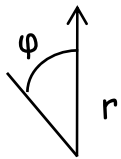


3D

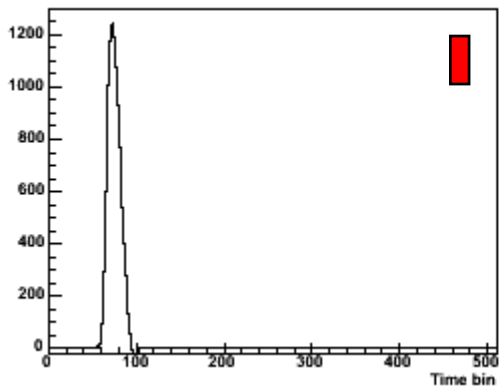


- RUN 284
- B = 1T
- T2K gas
- Peaking time: 100 ns
- Frequency: 25 MHz

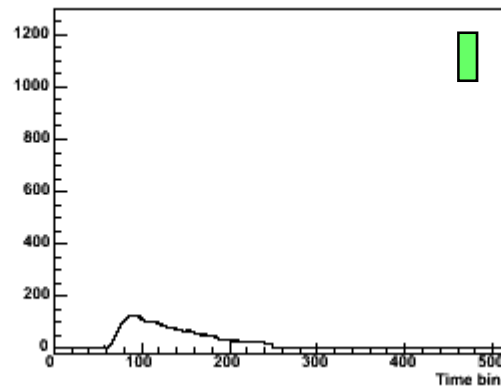




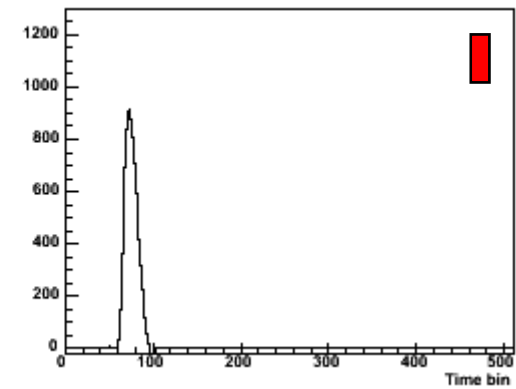
hADC 1084



hADC 1095

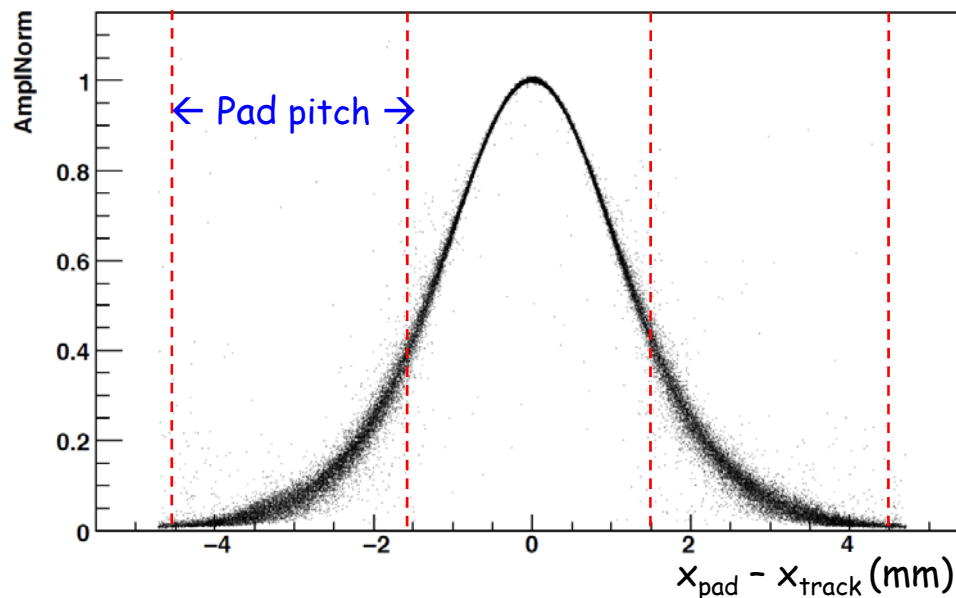


hADC 1099

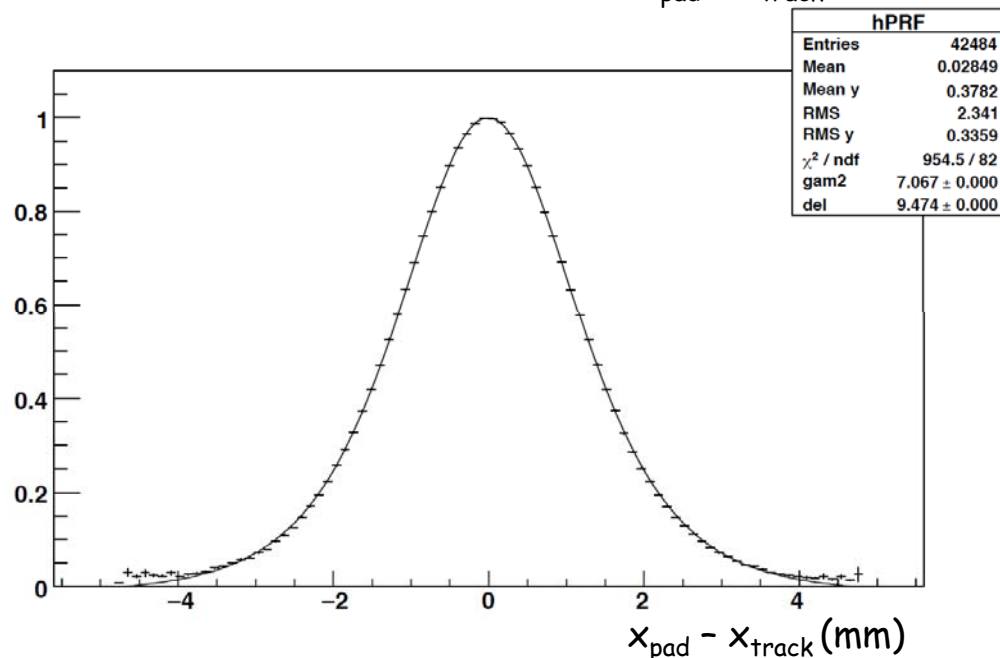


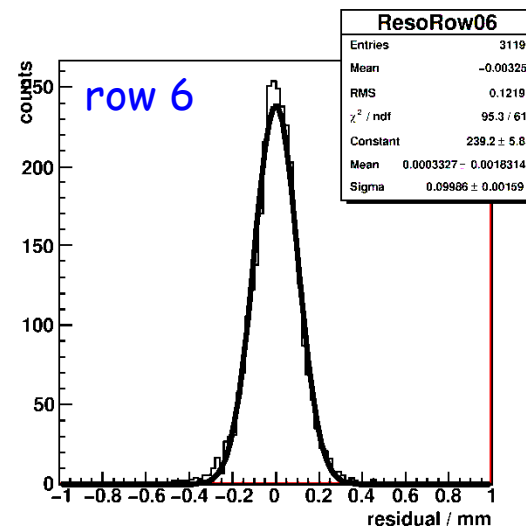
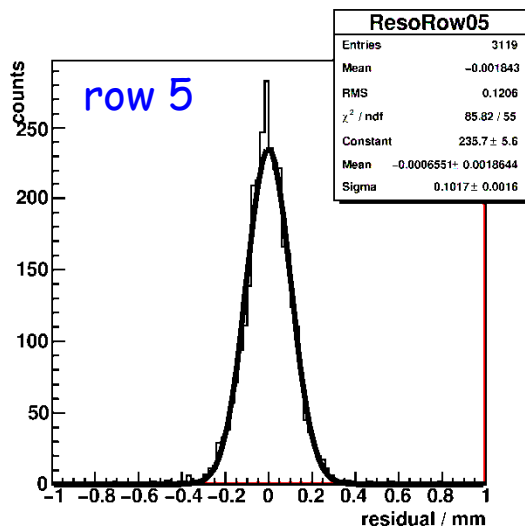
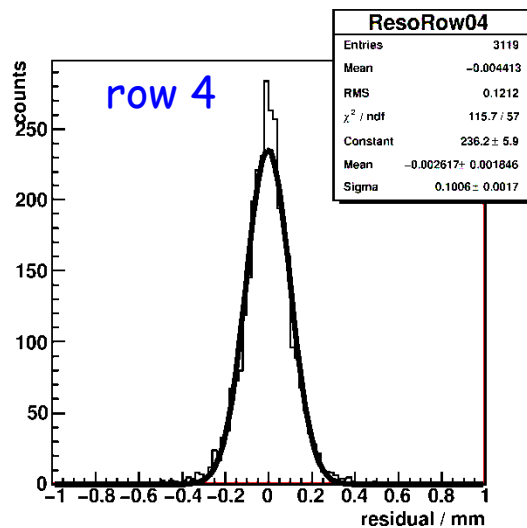
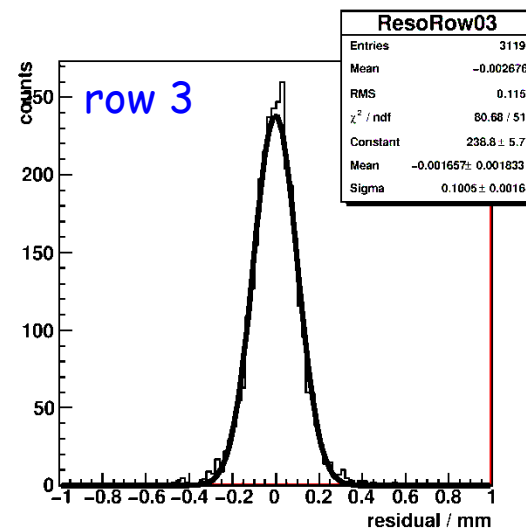
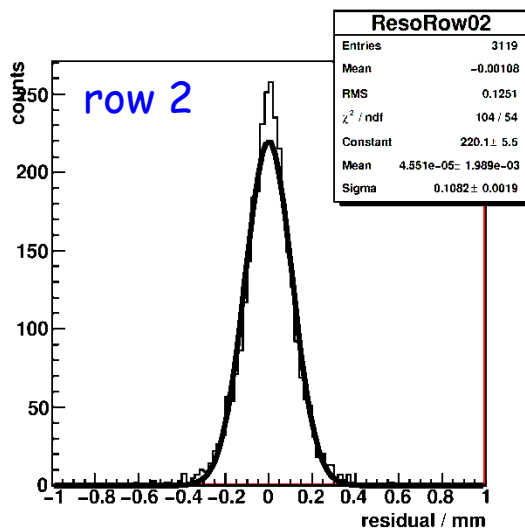
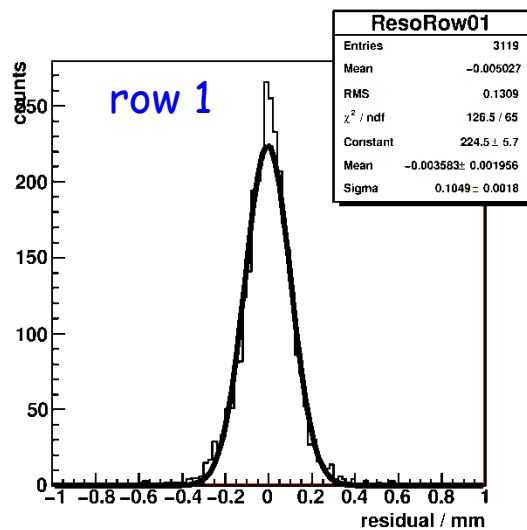
- Fraction of the row charge on a pad vs $x_{\text{pad}} - x_{\text{track}}$ (normalized to central pad charge)

→ Clearly shows charge spreading over 2-3 pads (data with 500 ns shaping)

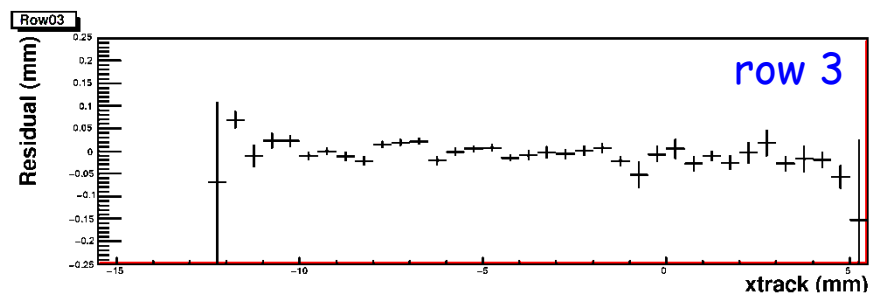
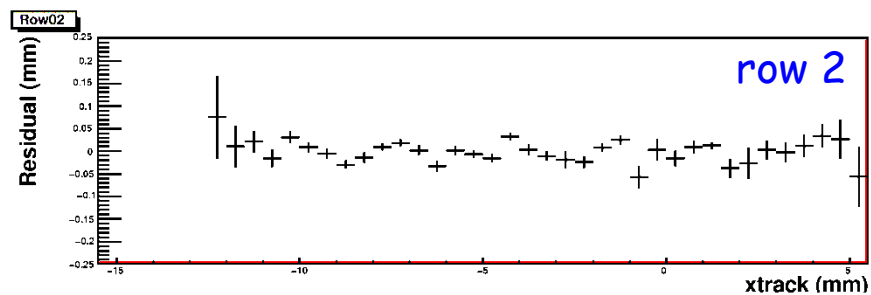
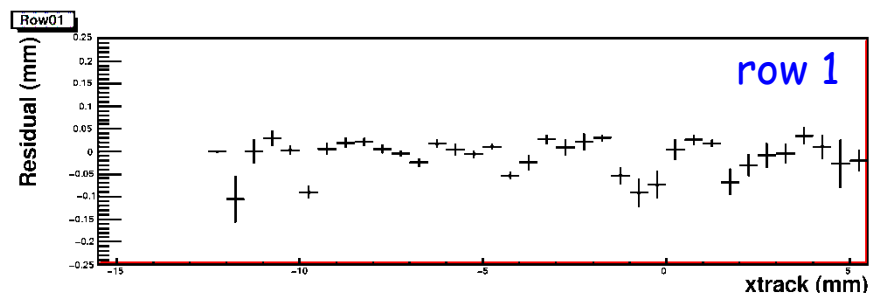
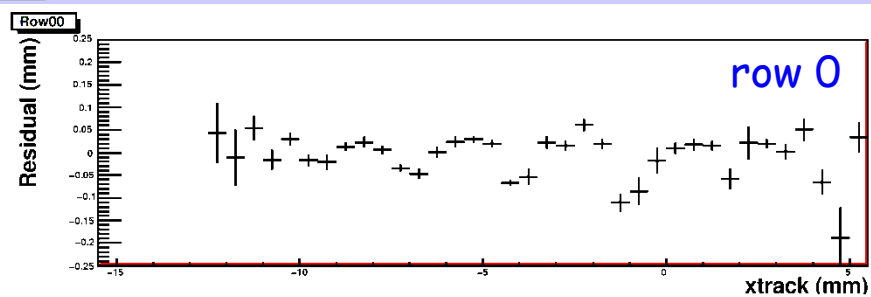


- Then fit $x(\text{cluster})$ using this shape with a χ^2 fit, and fit simultaneously all lines

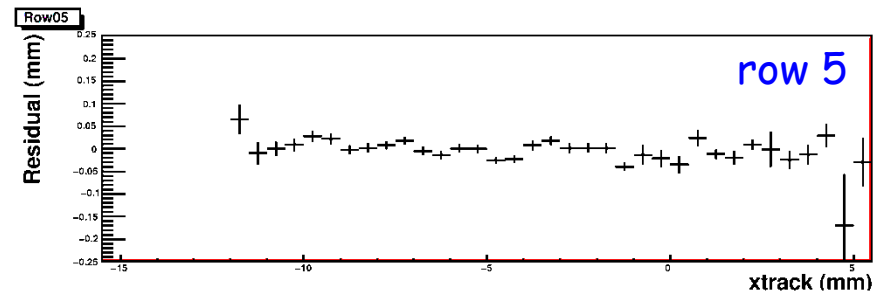
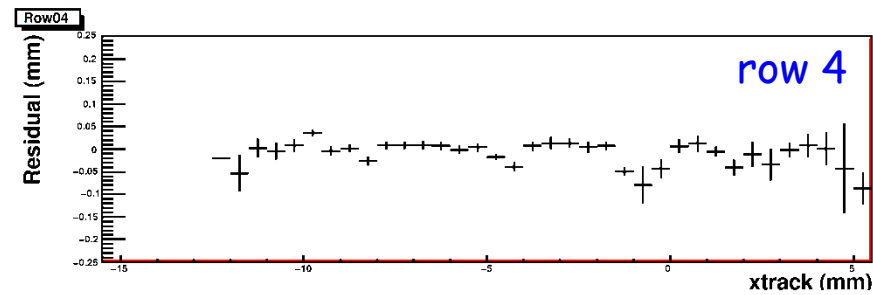




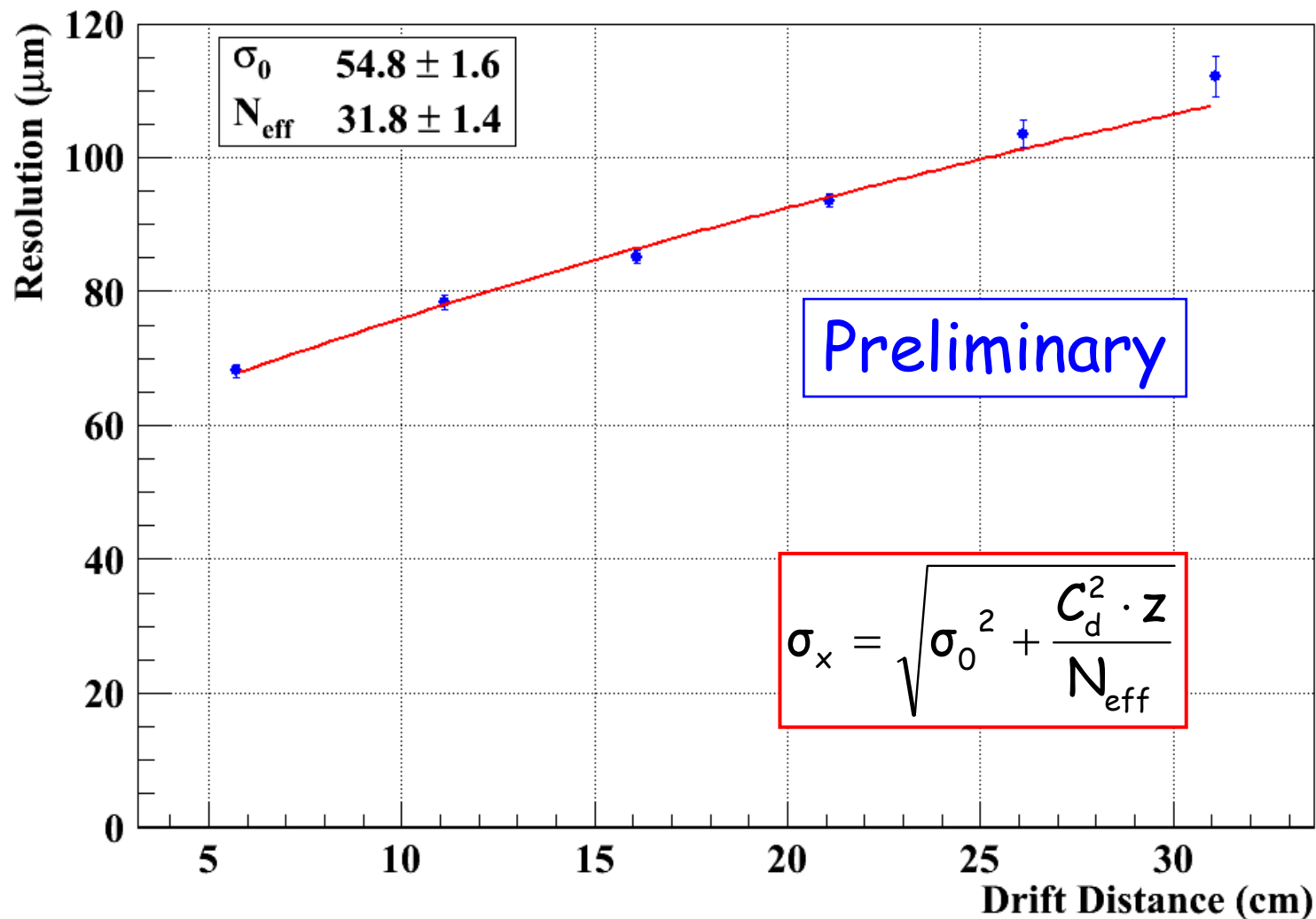
Residuals ($x_{\text{row}} - x_{\text{track}}$) are gaussians



- Bias remaining after correction:
mean of residual $x_{row} - x_{track} = f(x_{track})$
- Variation of up to 50 μm
- with a periodicity of about 3mm (pad width)

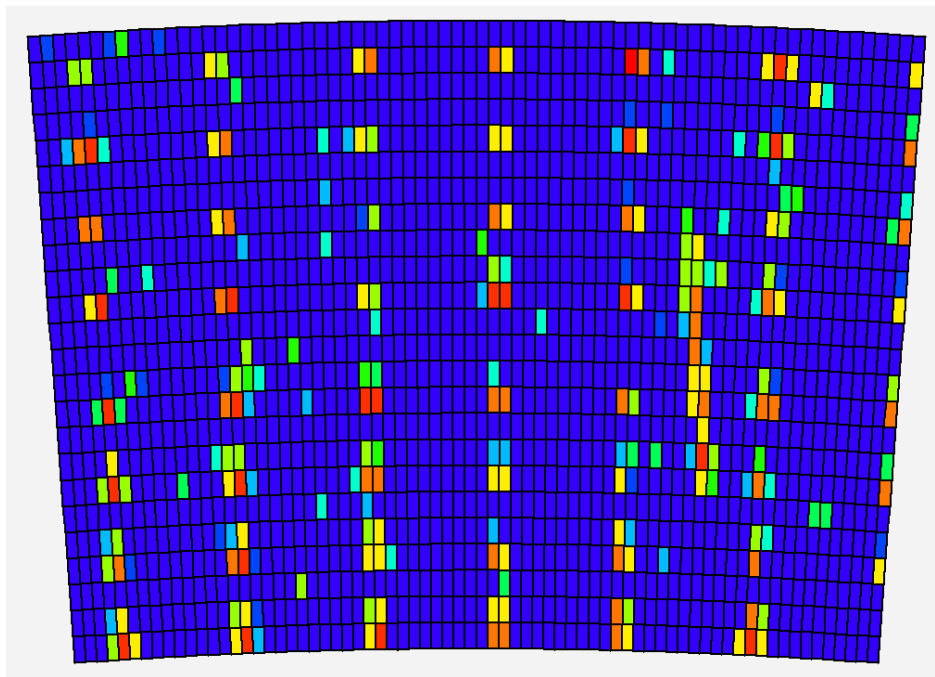


- Resolution at $z=0$: $\sigma_0 = 54.8 \pm 1.6 \mu\text{m}$ with 2.7-3.2 mm pads ($w_{\text{pad}}/55$)
- Effective number of electrons: $N_{\text{eff}} = 31.8 \pm 1.4$ consistent with expectations

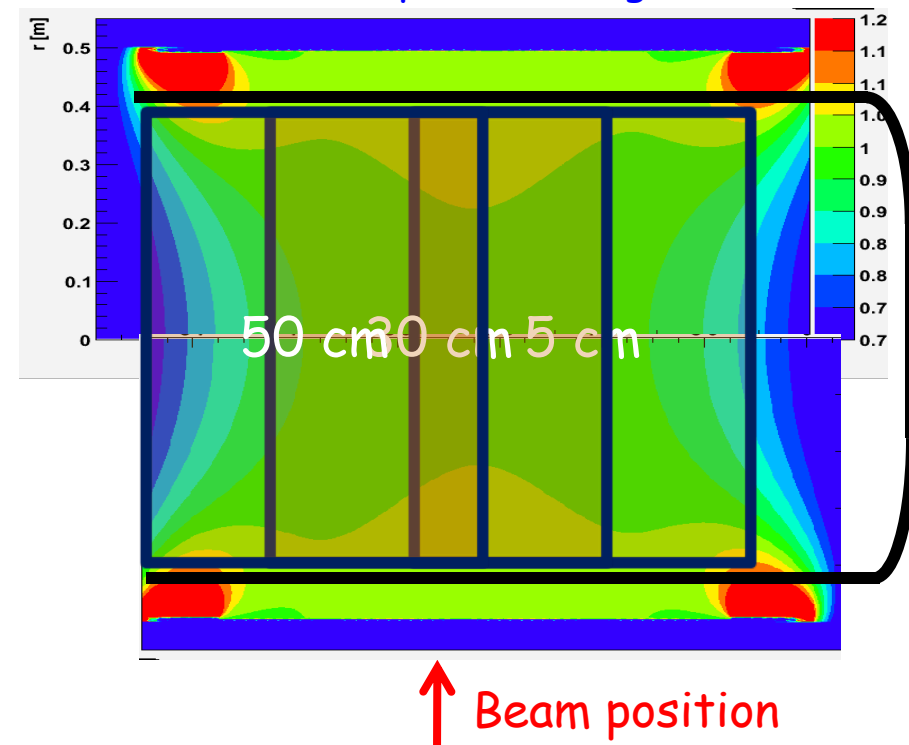


- two laser devices installed on the endplate to light up photosensitive pattern on the cathode (spots and line)
- deterioration of resolution at $z > 40$ cm : due to low field 0.9 to 0.7 T in the last 20 cm (significant increase of transverse diffusion)

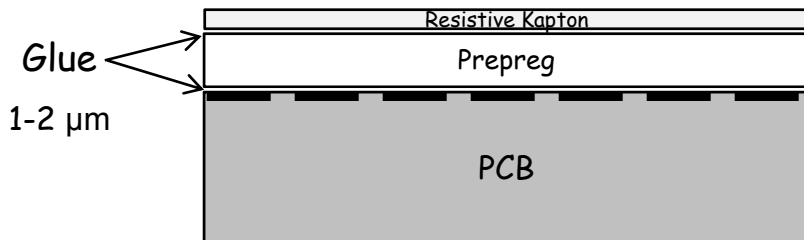
Photoelectrons from the cathode pattern



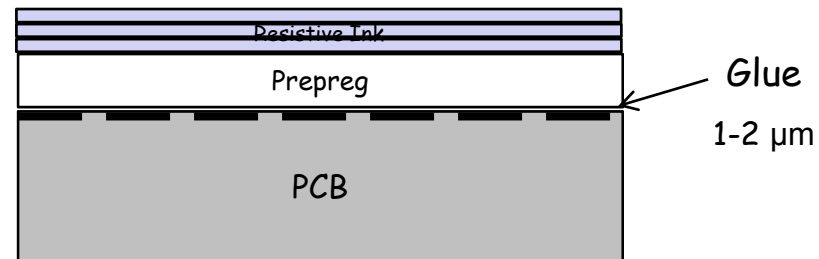
B field map of the magnet



Resistive Kapton



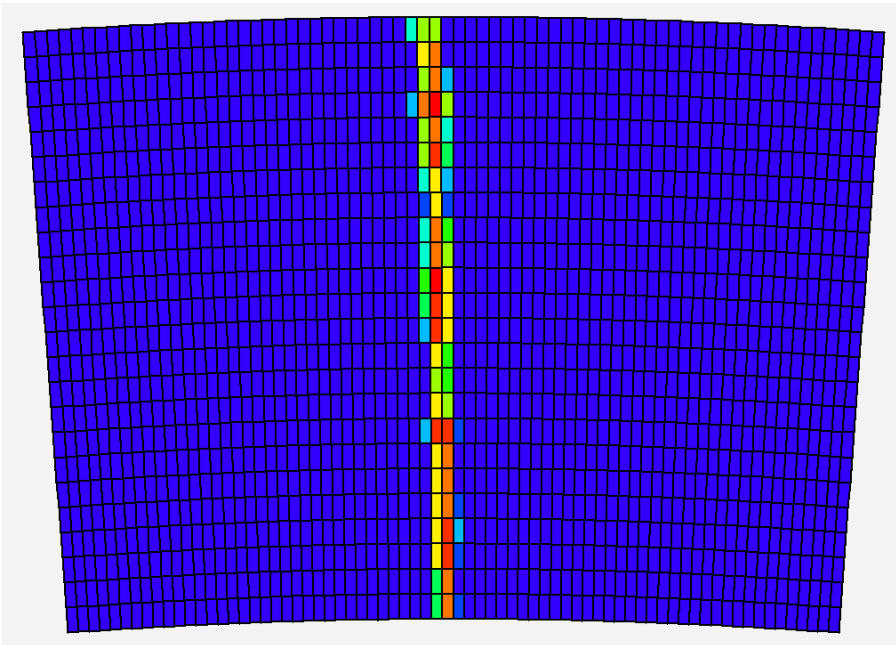
Resistive Ink



Detector	Dielectric layer	Resistive layer	Resistivity ($M\Omega/\square$)
Resistive Kapton	Epoxy-glass 75 μm	C-loaded Kapton 25 μm	~4-8
Resistive Ink	Epoxy-glass 75 μm	Ink (3 layers) ~50 μm	~1-2

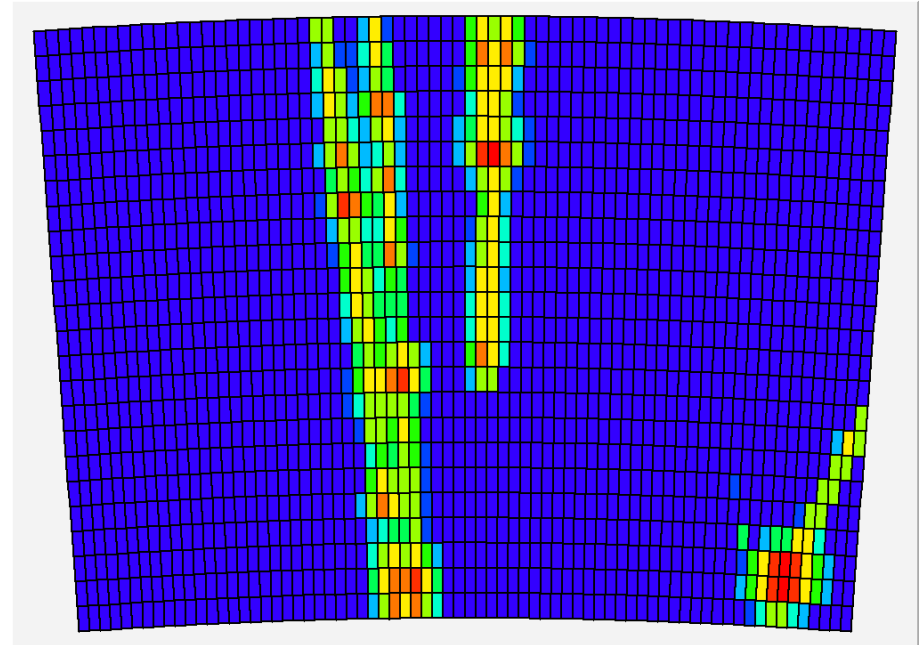
Resistive Kapton

- RUN 310
- $v_{\text{drift}} = 230\text{ cm}/\mu\text{s}$
- $V_{\text{mesh}} = 380\text{ V}$
- Peaking time: 500 ns
- Frequency Sampling: 25 MHz



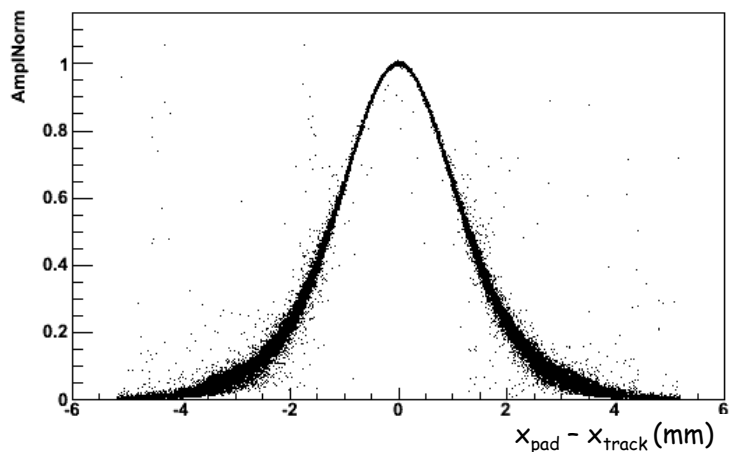
Resistive Ink

- RUN 549
- $V_{\text{drift}} = 230\text{ cm}/\mu\text{s}$
- $V_{\text{mesh}} = 360\text{ V}$
- Peaking time: 500 ns
- Frequency Sampling: 25 MHz

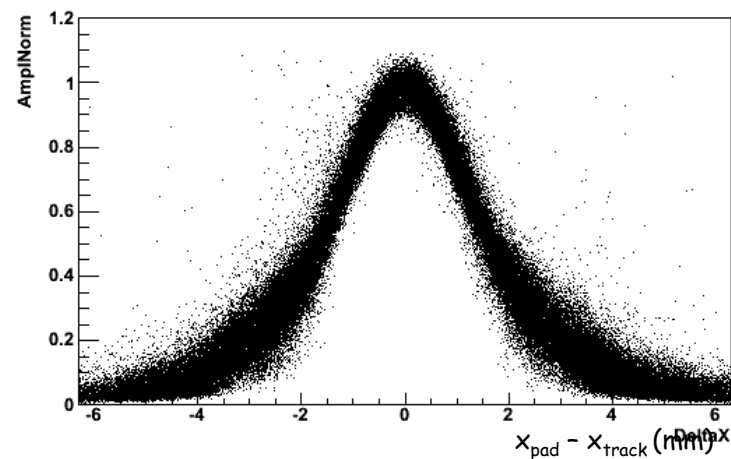


Resistive Kapton

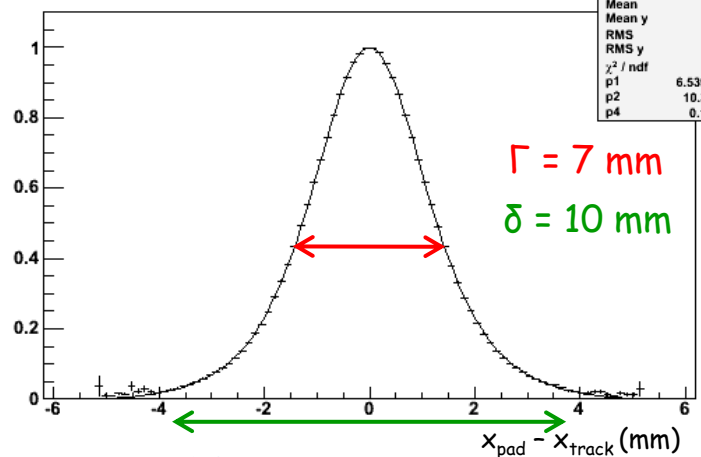
AmplNorm:DeltaX (AmplNorm<=1.1 && AmplNorm>=0 && abs(PhiFit)<5*3.1415927/180.)



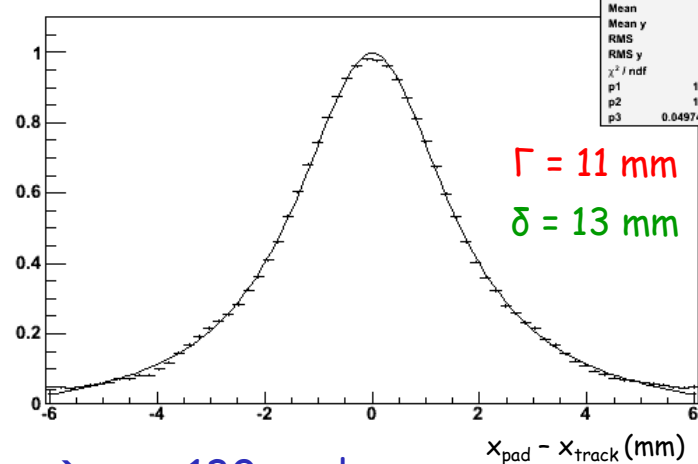
AmplNorm:DeltaX (AmplNorm<=1.1 && AmplNorm>=0 && abs(PhiFit)<5*3.1415927/180.)

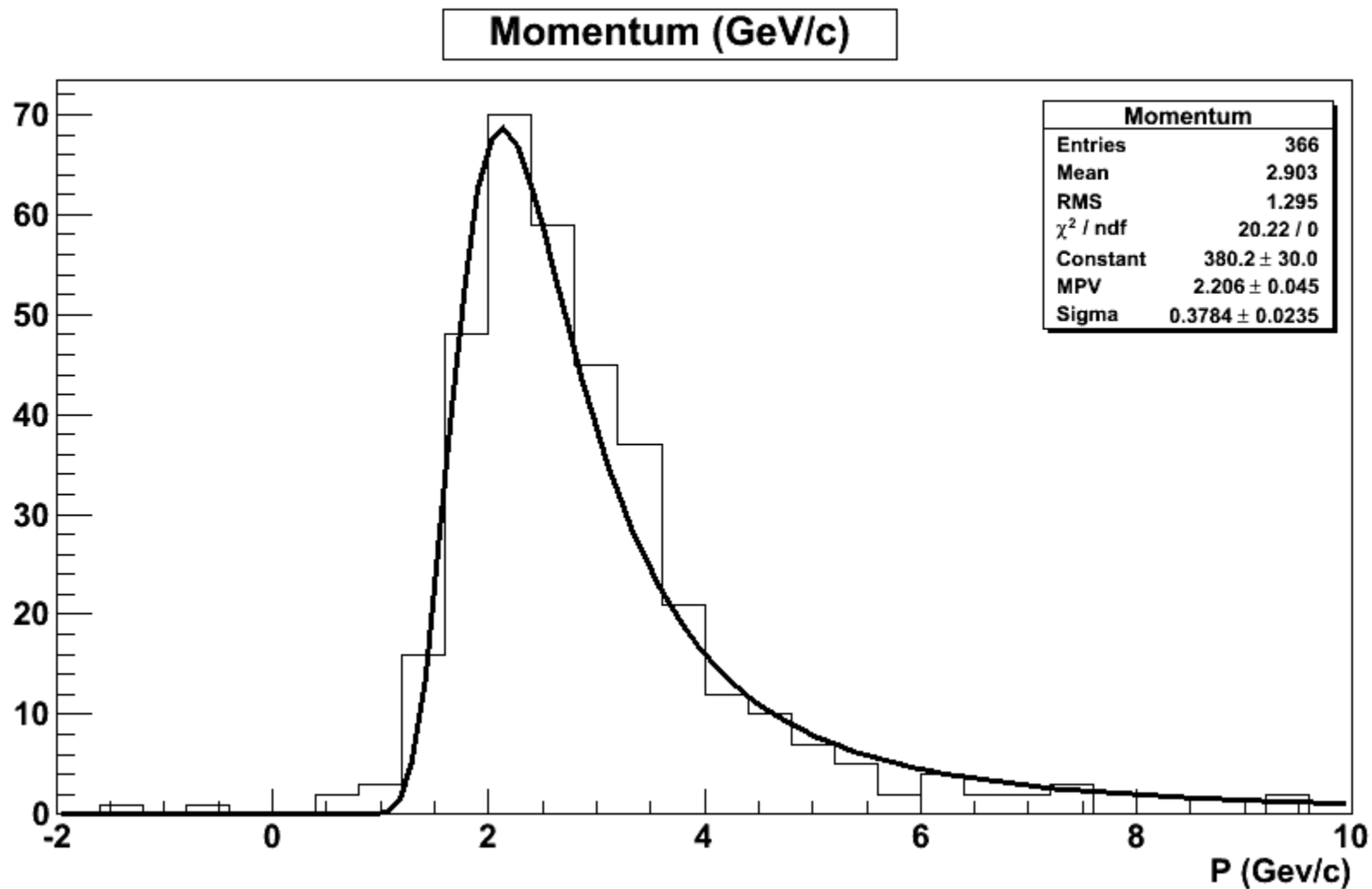


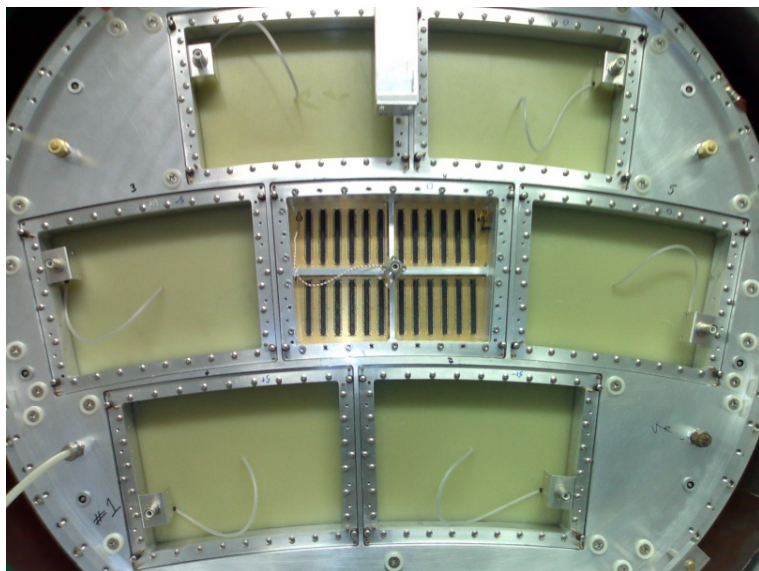
AmplNorm:DeltaX (AmplNorm<=1.1 && AmplNorm>=0 && abs(PhiFit)<5*3.1415927/180.)


 $\rightarrow \sigma_0 = 68 \mu\text{m}$

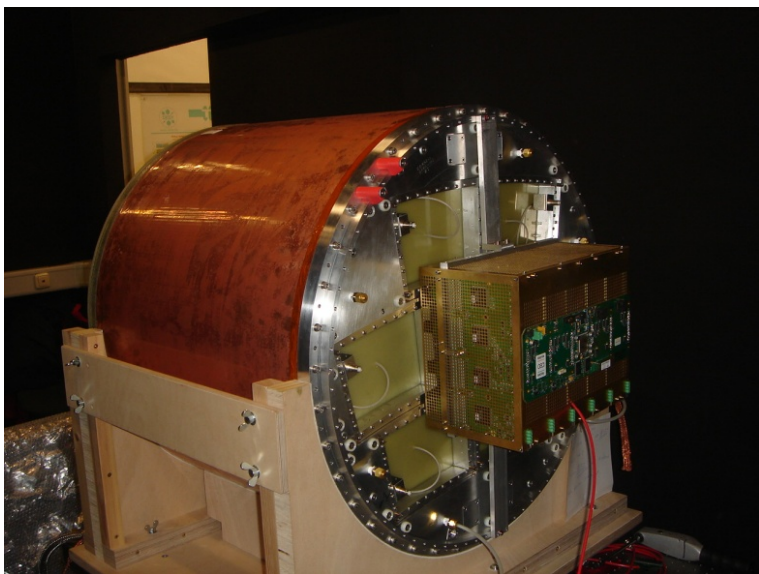
AmplNorm:DeltaX (AmplNorm<=1.2 && AmplNorm>=0 && abs(X0Fit)<3 && abs(PhiFit)<5*3.1415927/180.)


 $\rightarrow \sigma_0 = 130 \mu\text{m} !$



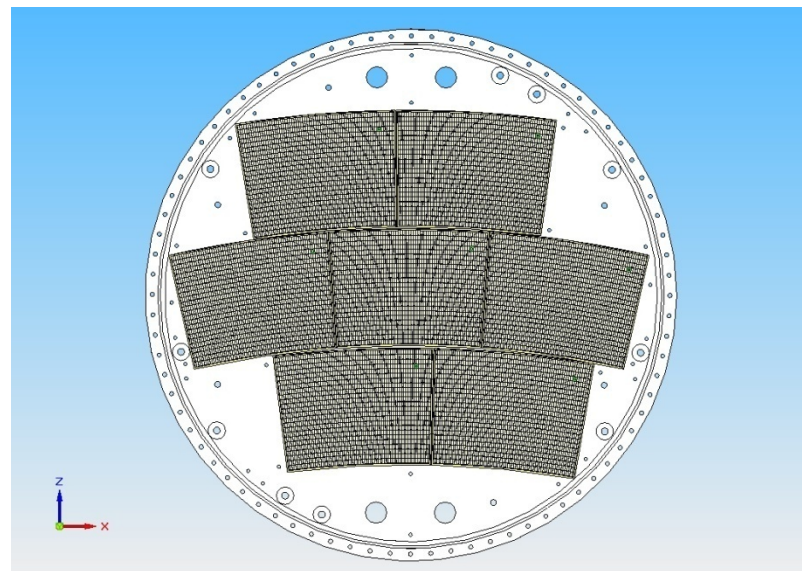
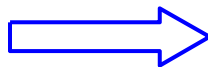


In 2008/2009 with one detector module

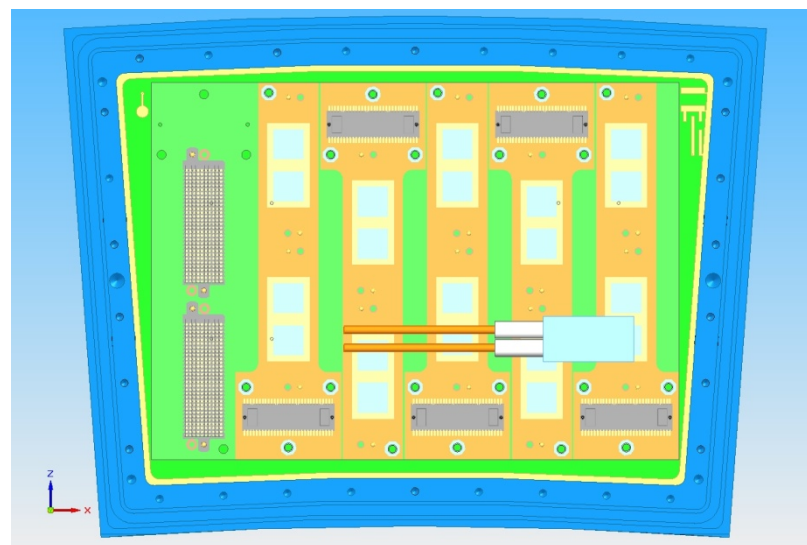


Reduce the electronic with possibility to bypass shaping

Resistive technology choice



In 2010 with 7 detector modules.



- Two Micromegas with resistive anode have been tested within the EUDET facility using 1T magnet to reduce the transverse diffusion
- C-loaded Katpon technology gives better result than resistive ink technology
- First analysis results confirm excellent resolution at small distance with the resistive C-loaded Kapton: **55 μm for 3 mm pads**
- The moving table is necessary to fix the inhomogeneous B field at high z
- Plans are to test several resistive layer manufacturing process and RC, then go to 7 modules with integrated electronics.
- Next step is making 2 new detectors, identical except the routing (we have 2 routings) both in CLP but a new, lower resistivity one. Should be close to ideal.

- Saclay, France:

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- Carleton Univ., Canada:

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- DESY/EUDET

